

Large anisotropic single crystal epitaxial graphene flakes isolated from SiC wafers

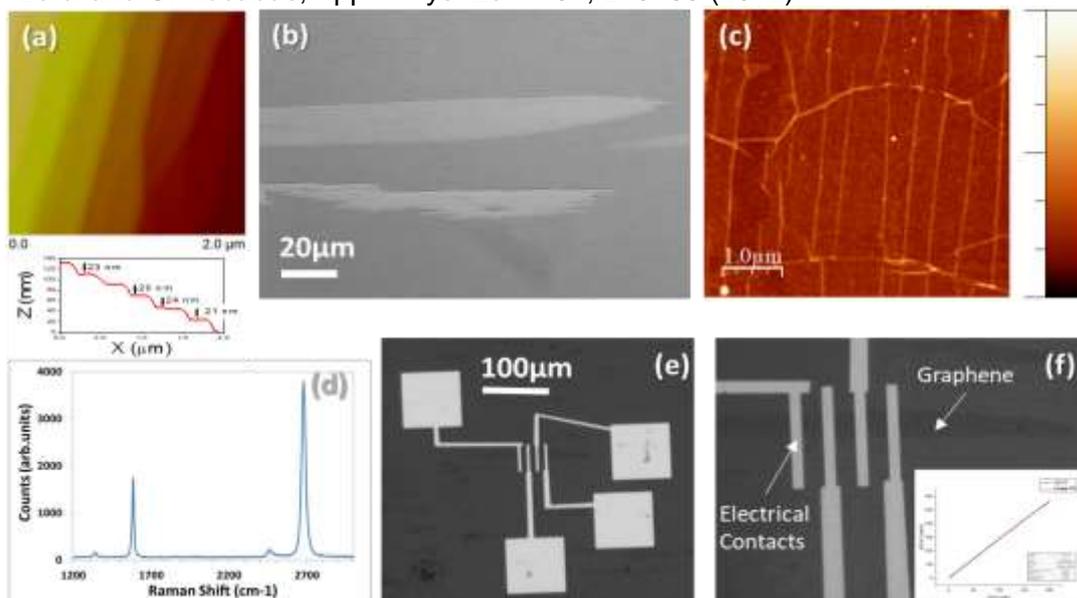
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Beyond fundamental studies on mechanically exfoliated HOPG, best electronic devices are based on high quality graphene obtained either by CVD on Cu foils or epitaxial graphene (EG) on SiC [1]. In this work, we report some preliminary results on the development of electrical devices based on large anisotropic single crystal EG flakes obtained on the C-face of SiC by high temperature sublimation [2]. The as-grown isolated EG flakes can be detached and transferred to e.g. SiO₂ substrate by PMMA-assisted electrochemical delamination technique, which is a non-destructive, reproducible and low-cost exfoliation method that has been adapted to EG on SiC [3]. For the fabrication of graphene electrical contacts simple alignment and patterning by e-beam lithography, thin film evaporation and resist lift off process was employed. As-deposited EG materials consist in hundreds- μm -long, tens-of- μm -wide SLG to FLG EG islands, covering typical regularly step-bunched SiC (Fig. 1 (a, b)). The transferred materials on SiO₂ somehow reproduce that SiC substrate terrace topography (Fig. 1(c)). Examples of Raman spectra of transferred EG are shown in (Fig. 1 (d)). The electrical characteristics have been tested via 4-probe method on three different devices. The linear I-V relationship reveals the presence of ohmic contacts displaying resistances ranging from 1.2k Ω to 2.3k Ω (Fig. 1 (f)). Yet, these values could be easily improved by applying dedicated treatments prior e.g. to metal deposition, such as plasma treatments [4] of the contact areas or post deposition treatments such as rapid thermal annealing [5]. Both structural and electronic characterization indicate that high crystalline quality of EG is basically preserved upon electrochemical transfer as well as device fabrication.

REFERENCES

- [1] Gemma Rius, Philippe Godignon. Epitaxial Graphene on Silicon Carbide, Modeling, Characterization, and Applications, Jenny Stanford Publishing, 2018.
- [2] N. Camara et al., Phys. Rev. B 80, 125410, 2009.
- [3] G.Rius Suñé, P. Godignon, R. Villa Sanz, E.Prats Alfonso. Method for Exfoliating and Transferring Graphene from a Doped Silicon Carbide Substrate to another Substrate, US20200031675 ,2020.
- [4] M. Sup Choi et al., Appl. Phys. Lett., 110, 073305, (2011).
- [5] O. Balci and C. Kocabas, Appl. Phys. Lett. 101, 243105 (2012).



Figures 1: (a) AFM image of as-grown EG on SiC; (b) optical image of as-grown EG on SiC; (c) AFM image of transferred EG on SiO₂ (Z scale=20nm); (d) exemplary Raman spectra after transfer; (e) optical image of a large anisotropic EG flake interfaced by 4 probes electrical device; (f) optical image and electrical characteristics a SLG/BLG electronic device.